

# United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.usplo.gov

DATE MAILED: 03/29/2004

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/724,146	11/28/2000	Mike Binnard	PA0324-US\I 1269.21	6125
25944 7	590 03/29/2004	EXAMINER		INER
OLIFF & BERRIDGE, PLC			STOCK JR, GORDON J	
P.O. BOX 1992	-		ART UNIT	PAPER NUMBER
ALEXANDRIA, VA 22320			2877	

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	09/724,146	BINNARD ET AL.				
Office Action Summary	Examiner	Art Unit				
	Gordon J Stock	2877				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the	correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period we Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	6(a). In no event, however, may a reply be ti within the statutory minimum of thirty (30) da fill apply and will expire SIX (6) MONTHS fron cause the application to become ABANDONI	mely filed ys will be considered timely. n the mailing date of this communication. ED (35 U.S.C. § 133).				
Status /		•				
1) Responsive to communication(s) filed on <u>09 De</u>	ecember 2003.					
2a) This action is <b>FINAL</b> . 2b) ☑ This	<u></u>					
, , <del> </del>	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims						
4) ☐ Claim(s) 1-5,7-13,16-30 and 32-44 is/are pendid 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-5,7-13,16-30,32-38,43 and 44 is/are 7) ☐ Claim(s) 39-42 is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	vn from consideration.  c rejected.					
Application Papers						
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) access Applicant may not request that any objection to the confidence of Replacement drawing sheet(s) including the correction of the original transfer of the confidence of the confidenc	epted or b) objected to by the drawing(s) be held in abeyance. So ion is required if the drawing(s) is o	ee 37 CFR 1.85(a). bjected to. See 37 CFR 1.121(d).				
Priority under 35 U.S.C. § 119						
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the prior application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Applica ity documents have been receiv ı (PCT Rule 17.2(a)).	tion No ved in this National Stage				
Attachment(s)  1) Notice of References Cited (PTO-892)  2) Notice of Draftsperson's Patent Drawing Review (PTO-948)  3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date	4) Interview Summar Paper No(s)/Mail [5] Notice of Informal 6) Other:					

Application/Control Number: 09/724,146

Art Unit: 2877

#### **DETAILED ACTION**

#### Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1-5, 7-13, 16-30, 32-34 are rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi (5,243,195) in view of Nara et al. (5,523,841) and Yao (6,057,921).

As for claims 1-5, 7-13, 16-30, 32-34, Nishi in a projection exposure apparatus discloses a moveable stage for a wafer; a moveable reticle stage, a secondary stage, that suggests having x-mirror and y-mirrors with three interferometric measurement systems for the reticle stage; a wafer stage with a plurality of fiducial marks and three interferometric measurement systems with an x and y mirror. As for a controller that utilizes the marks to determine the positions of the respective mirrors, Nishi discloses a main control system (Fig. 7, 114) and discloses that the system finds the positions of the mirrors and marks in relation to each other for reticle alignment with the substrate (col. 5, lines 5-45). As for first and second detectors, Figs. 1, 7, 8 demonstrate at least two alignment detection schemes.

As for a secondary x-mirror, Nishi is silent. However, Yao in a two piece mirror arrangement for interferometrically controlled stage teaches a secondary x-mirror comprising one of the sides of the y-mirrors for proper calibration of the mirrors and to adequately determine their positions relative to each other (Fig. 2; col. 3, lines 5-35). And Nara in a distance measuring apparatus teaches using two x-mirrors rather than one to enlarge the area within which

Application/Control Number: 09/724,146

Art Unit: 2877

the x-y stage moves without enlarging the dimensions of the movable mirrors with two x interferometric systems for each mirror (col. 2, lines 10-30; Fig. 2).

Therefore, it would be obvious to one skilled in the art at the time the invention was made to have two x-mirrors in order to provide more freedom of movement for the stage and to have a secondary x-mirror be part of the y-mirror to adequately calibrate each mirror's position in relation to each other.

3. Claim 35 is rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi (5,243,195) in view of Nara et al. (5,523,841) and Yao (6,057,921) further in view of Ueda (5,417,408).

As for claim 35, see claim 13. They are silent about cantilevers. However, Ueda in a stage teaches using cantilevers for movement (col. 3, lines 30-40). Therefore, it would be obvious to one skilled in the art to have the stage comprise cantilevers in order for the stage to move.

4. Claim 36 is rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi (5,243,195) in view of Nara et al. (5,523,841) and Yao (6,057,921) further in view of Nishi (WO 200022376).

As for claim 36, see claim 13. In addition, Nishi discloses a plurality of fiducial marks (Fig. 23) and two 2-dimensional fiducial marks (Fig. 2). However, he is silent concerning three 2-dimensional marks. Nishi in a shape measuring method and device teaches using six 2-dimensional reference marks for better alignment (Fig. 2). Therefore, it would be obvious to one skilled in the art at the time the invention was made to have more than two 2-dimensional fiducial marks to improve accuracy of alignment.

The state of the s

Application/Control Number: 09/724,146

Art Unit: 2877

5. Claims 37-38, 44 are rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi (5,243,195) in view of Nara et al. (5,523,841) and Yao (6,057,921) further in view of Matsui (6,404,505).

As for claims 37-38, see claim 13. In addition, Fig. 2 suggests that mirrors are used with the reticle stage's interferometric systems. However, Nishi does not disclose suggest a secondary x-mirror for the reticle stage. As for a secondary x-mirror, Nishi is silent. However, Yao in a two piece mirror arrangement for interferometrically controlled stage teaches a secondary x-mirror comprising one of the sides of the y-mirrors for proper calibration of the mirrors and to adequately determine their positions relative to each other (Fig. 2; col. 3, lines 5-35). And Nara in a distance measuring apparatus teaches using two x-mirrors rather than one to enlarge the area within which the x-y stage moves without enlarging the dimensions of the movable mirrors with two x interferometric systems for each mirror (col. 2, lines 10-30; Fig. 2).

Therefore, it would be obvious to one skilled in the art at the time the invention was made to have two x-mirrors in order to provide more freedom of movement for the stage and to have a secondary x-mirror be part of the y-mirror to adequately calibrate each mirror's position in relation to each other.

In addition, Matsui in a positioning stage system teaches using two x-mirrors for reticle stage to substrate stage alignment (Fig. 1). Therefore, it would be obvious to one skilled in the art at the time to have a secondary x-mirror for proper alignment between a reticle stage and substrate stage.

As for claim 44, Nishi discloses a plurality of two-dimensional marks (RM1 and RM2 of Fig. 2).

Application/Control Number: 09/724,146

Art Unit: 2877

6. Claim 43 is rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi (5,243,195) in view of Nara et al. (5,523,841) and Yao (6,057,921) further in view of Matsui (6,404,505) and further in view of Ueda (5,417,408).

As for claim 43, see claim 37. They are silent about cantilevers. However, Ueda in a stage teaches using cantilevers for movement (col. 3, lines 30-40). Therefore, it would be obvious to one skilled in the art to have the stage comprise cantilevers in order for the stage to move.

## Allowable Subject Matter

7. Claims 39-42 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

As to claim 39, the prior art of record, taken alone or in combination, fails to disclose or render obvious in an exposure apparatus a replacer that replaces the first and second movable stages with respect to the first and second position detectors, in combination with the rest of the limitations of claims 39-42.

#### Response to Arguments

8. Applicant's arguments with respect to the claims have been considered but are moot in view of the new ground(s) of rejection. As for the allowable subject matter as set forth in the prior office action, the Examiner apologizes for the inconvenience caused by the grounds of rejection, but after performing an updated search, the Examiner found new grounds of rejection for the claims.

## Fax/Telephone Numbers

If the applicant wishes to send a fax dealing with either a proposed amendment or a discussion with a phone interview, then the fax should:

- 1) Contain either a statement "DRAFT" or "PROPOSED AMENDMENT" on the fax cover sheet; and
  - 2) Should be unsigned by the attorney or agent.

This will ensure that it will not be entered into the case and will be forwarded to the examiner as quickly as possible.

Papers related to the application may be submitted to Group 2800 by Fax transmission. Papers should be faxed to Group 2800 via the PTO Fax machine located in Crystal Plaza 4. The form of such papers must conform to the notice published in the Official Gazette, 1096 OG 30 (November 15, 1989). The CP4 Fax Machine number is: (703) 872-9306

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Gordon J. Stock whose telephone number is (571) 272-2431. The examiner can normally be reached on Monday-Friday, 10:00 a.m. - 6:30 p.m.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

gs March 21, 20

March 21, 2004

Primary Examiner